



- (3506) 250/281 250/288
- (3) ("4570060" | "4667100" | "5157260").PN.
- (474) (250/281 250/288) and heater
- (4910) remov\$ and electrospray
- (328) removable and electrospray
- (2) removable near3 electrospray
- (3) ("5306412" | "5788166" | "6127680").PN.
- (376) apci and electrospray
- (460) 250/455.11
- (113) 250/455.11 and electron
- (6) ("4075496" | "4201920" | "4252413" | "4281251" | "4492873" | "5004926").PN.
- (1) wo99/00801
- (0) "9900801"
- (5) anderberg and irradiation
- (8) anderberg and irradiation
- (9) "9900801"
- (31) 250/455.11 and electron and (computer microprocessor)
- (325) (arc near3 chamber) and alumina
- (19) (arc near3 chamber) and (alumina near3 insulat\$4)

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II and alumina

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3	<input type="checkbox"/>	<input type="checkbox"/>	US 20030122089 A1	20030703	15	Ion sources for ion implantation apparatus	250/492.21	250/423R; 250/425	Murre
4	<input type="checkbox"/>	<input type="checkbox"/>	US 20030042436 A1	20030306	49	Discharge electrode and discharge electrode manufacturing method	250/493.1		Hori
5	<input type="checkbox"/>	<input type="checkbox"/>	US 20030042435 A1	20030306	9	Powdered far-Infrared radiator and method of making the same	250/493.1		Imai, I
6	<input type="checkbox"/>	<input type="checkbox"/>	US 20030038245 A1	20030227	13	Field ionizing elements and applications thereof	250/423R	250/287; 250/288;	Hartle
7	<input type="checkbox"/>	<input type="checkbox"/>	US 20020056816 A1	20020516	18	Surface plasmon enhanced illumination system	250/493.1		Stark, Hazar
8	<input type="checkbox"/>	<input type="checkbox"/>	US 6617810 B2	20030909	11	Multi-stage cavity cyclotron resonance accelerators	315/500	250/292; 250/423R;	Symo
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10	<input type="checkbox"/>	<input type="checkbox"/>	US 6610986 B2	20030826	10	Soft ionization device and applications thereof	250/423R	250/286; 250/287;	Hartle
11	<input type="checkbox"/>	<input type="checkbox"/>	US 6597004 B2	20030722	9	Powdered far-Infrared radiator and method of making the same	250/493.1	250/495.1; 252/500;	Imai, I
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